



MAIL STOP PCT

IFW

Docket No. 288992US0PCT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Yasuo MATSUKI, et al.

SERIAL NO: 10/575,478

GAU:

FILED: April 12, 2006

EXAMINER:

FOR: COMPOSITION FOR FORMING SILICON-COBALT FILM, SILICON-COBALT FILM AND METHOD FOR FORMING SAME

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

SIR:

Applicant(s) wish to disclose the following information.

REFERENCES

- ☒ The applicant(s) wish to make of record the references listed on the attached form PTO-1449. Copies of the listed references are attached, where required, as are either statements of relevancy or any readily available English translations of pertinent portions of any non-English language references.
- ☐ A check or credit card payment form is attached in the amount required under 37 CFR §1.17(p).

RELATED CASES

- ☐ Attached is a list of applicant's pending application(s), published application(s) or issued patent(s) which may be related to the present application. In accordance with the waiver of 37 CFR 1.98 dated September 21, 2004, copies of the cited pending applications are not provided. Cited published and/or issued patents, if any, are listed on the attached PTO form 1449.
- ☐ A check or credit card payment form is attached in the amount required under 37 CFR §1.17(p).

CERTIFICATION

- ☐ Each item of information contained in this information disclosure statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.
- ☐ No item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned, having made reasonable inquiry, was known to any individual designated in 37 CFR §1.56(c) more than three months prior to the filing of this statement.

DEPOSIT ACCOUNT

- ☒ Please charge any additional fees for the papers being filed herewith and for which no check or credit card payment is enclosed herewith, or credit any overpayment to deposit account number 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

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Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 288992US0PCT		SERIAL NO. 10/575,478	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Yasuo MATSUKI, et al.			
				FILING DATE April 12, 2006		GROUP	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
	AO	4-53512	02/21/92	JP		NO	
	AP	53-60171	05/30/78	JP (with English translation)		NO	
	AQ	1999/022411	05/06/99	WO (with English abstract & equivalent of US6506321)		NO	
	AR	2000/059040	10/05/00	WO (with English abstract & equivalent of US6514801)		NO	
	AS	3382743	12/20/02	JP (with Computer generated translation)		NO	
	AT	4-53132	02/20/92	JP (with Computer generated translation & equivalent of JP2980645)		NO	
	AU						
	AV						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
	AW	SADOH, Taizoh et al., "High-Performance MOS Tunneling Cathode with CoSi ₂ Gate Electrode", Jpn. J. Appl. Phys., Vol. 40, Part 1, No. 4B, Pages 2775-2778, 2001.					
	AX	ZAIMA, Shigeaki et al., "Formation of silicide at metal/silicon interface and low-resistivity contacts", Applied Physics, Vol. 63, No. 11, Pages 1093-1105, 1994. (with English abstract)					
	AY						
	AZ					<input type="checkbox"/> Additional References sheet(s) attached	
Examiner					Date Considered		
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							